

Supplemental Data for:

“Domain State Exchange Bias in a Single Layer FeRh Thin Film Formed via Low Energy Ion Implantation”

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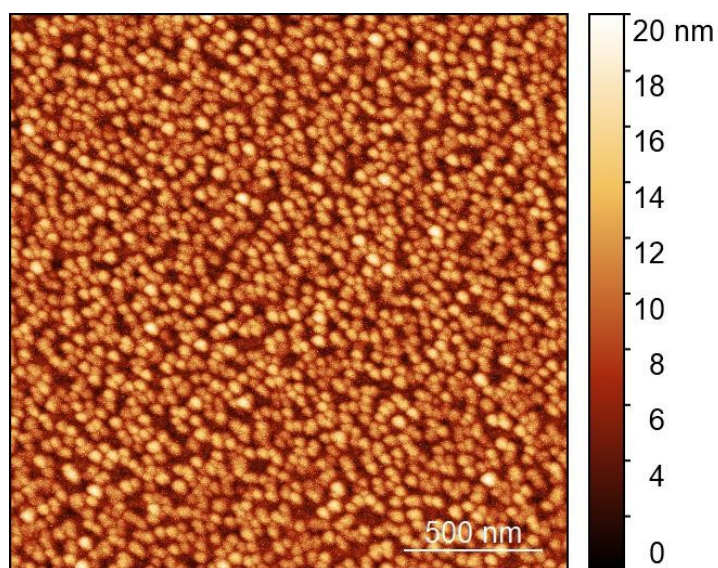


Figure S1: AFM image of FeRh film surface after 1keV Fe⁺ Ion irradiation